FORM PTO - 1449	ATTORNEY DOCKET NO.: IBX-008
INFORMATION DISCLOSURE STATEMENT	APPLICANT(S): Card et al.
	SERIAL NO.: 10/656,607
	FILING DATE: 9/5/03 GROUP: Not yet assigned

U.S. PATENT DOCUMENTS

EXAM. INIT.		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
(init.)	A1	5,467,883	11/21/95	Frye et al.	216	60	11/27/93
(init.)	A2	5,559,690	9/24/96	Keeler et al.	364	164	9/16/94
(init.)	A3	5,654,903	8/5/97	Reitman et al.	364	551.01	11/7/95
(init.)	A4	5,740,033	4/14/98	Wassick et al.	364	149	10/13/92
(init.)	A5	6,268,226	7/31/01	Angell et al.	438	16	6/30/99

FOREIGN PATENT DOCUMENTS

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(init.)	B1	WO 01/57605	8/9/01	WO	G05B	13/04	1/11/01	N	Y
(init.)	B2	DE196 37 917 A1	3/19/98	DE	G05B	13/04	9/17/96	Y	

OTHER ART, JOURNAL ARTICLES, ETC.

EXAM. INIT.		OTHER DOCUMENTS: (Including Author, Title, Date, Relevant Pages, Place of Publication)
(init.)	C1	Card et al., "Dynamic Neural Control for Plasma Etch Process," IEEE Transactions on Neural Networks, (1997).
(init.)	C2	Card et al., "Impacts of Maintenance Input on the Prediction Accuracy of an APC Controller," Presentation at AEC/APC Symposium XIV (September 9-11, 2002).
(init.)	C3	Card et al., "Advanced Analysis of Dynamic Neural Control Advisories for Process Optimization and Parts Maintenance," Presentation at AEC/APC Symposium XIV (September 9-11, 2002).
(init.)	C4	Dillon et al., "Guest Editorial Everyday Applications of Neural Networks," IEEE Transactions on Neural Networks, 8:4 (July 1997).
(init.)	C5	Hatzipantelis et al., "Comparing Hidden Markov Models with Artificial Neural Network Architectures for Condition Monitoring Applications," Artificial Neural Networks, 26-28, Conference Publication No. 409 (June 1995).

	C6	Kim et al., "Intelligent Control of Via Formation by Photosensitive BCB for MCM-L/D Applications," <u>IEEE Transactions on Semiconductor Manufacturing</u>, 12:503 (1999).
	C7	Konstantopoulos et al., "Controllers with Diagnostic Capabilities. A Neural Network Implementation. Journal of Intelligent and Robotic Systems," Department of Electrical Engineering, University of Notre Dame, IN 12: 197-228 (1995).
	C8	Moyne, "AEC/APC Vision: A Research and Suppliers' Point of View," 3rd Annual European AEC/APC Conference Proceedings (2002).
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